

Supplementary materials

CeO₂ nanofibers for *in-situ* O₂ and CO sensing in harsh environment

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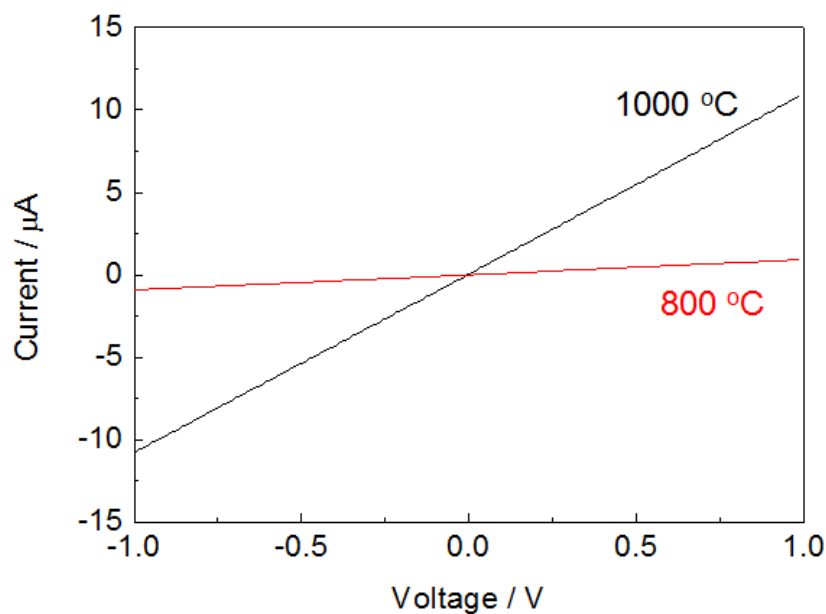


Figure S1. *I-V* profiles of CeO₂ nanofibers-based sensor at 800 and 1000 °C.

Table S1. Sensing performance of various resistor-type CO sensors

	Operating T/ °C	Carrying gas	C _{CO} * /ppm	Sensitivity (R ₀ /R _g)	Response time t ₉₀ /s	Ref.
Anatase/La ₂ O ₃ /CuO	600	N ₂ +5%O ₂	200	1.8	-	[1]
Anatase/La ₂ O ₃ /CuO	600	N ₂	250	4	-	[2]
SnO ₂	250	N ₂ +10%O ₂	6000	~1.3	30	[3]
Pt/SnO ₂	150	air	600	55	-	[4]
Pt/SnO ₂	400	air	10	2.3	6	[5]
CuO/ZnO/SnO ₂	200	air	200	8	-	[6]
Au/SnO _x	200	wet air	100	6.5	133	[7]
CuO/Zn ₂ SnO ₄	300	air	200	14	-	[8]
SnO ₂ / Zn ₂ SnO ₄	350	air	200	12	-	[9]
BaSnO ₃	650	N ₂	5000	3	-	[10]
CeO ₂	450	air	5000	3.1	2	[11]
Au/SnO ₂ /Ga ₂ O ₃	600	wet air	100	2.2	~ 60	[12]
La _{0.9} Ce _{0.1} CoO ₃	100	air	100	3.4 (R _g /R ₀)	-	[13]
LaCoO ₃ -PdO	200	air	100	16(R _g /R ₀)	-	[14]
ZnO	350	air	250	8	-	[15]
Al/ZnO	400	air	1000	2.5	-	[16]
ZnO-ITO	350	air	100	60	-	[17]
ZnO-ITO	500	air	100	8	-	[17]
Present work	800	N ₂	100	48.3	130	
	1000	N ₂	100	29.7	142	

* The concentration of CO which was used to calculate the sensitivity in each paper.

The sensitivity of the previous reported sensors were recalculated based on the data presented in the papers. The best result of each paper was chosen.

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